



micromachines



an Open Access Journal by MDPI

Accelerometer and Magnetometer: From Fundamentals to Applications, 2nd Edition

Guest Editors:

Prof. Dr. Liangcheng Tu

TianQin Research Center for
Gravitational Physics, School of
Physics and Astronomy, Sun Yat-
sen University, Zhuhai 519082,
China

Prof. Dr. Huafeng Liu

PGMF and School of Physics,
Huazhong University of Science
and Technology, Wuhan 430074,
China

Deadline for manuscript
submissions:

30 June 2024

Message from the Guest Editors

Dear Colleagues,

Accelerometers and magnetometers are widely applied in consumer electronics, automobiles, precision manufacturing and defense, aerospace and geophysical functions. MEMS technology can meet these applications' requirements of Cost, Size, Weight and Power (CSWaP) and performance, although some sensors still demonstrate scientific barriers to such uses. Key challenges include, but are not limited to, the following: microfabrication processes, new materials, device design and optimization, interface circuits, signal processing and sensor fusions. In addition, the promising new mechanisms of micromachines, such as atomic, optical levitation and optomechanical technologies, are of great interest. This Special Issue calls for original research papers and reviews detailing state-of-the-art results on the present topic.

Prof. Dr. Liangcheng Tu

Prof. Dr. Huafeng Liu

Guest Editors



mdpi.com/si/193667

Special Issue



Editor-in-Chief

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility: indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank: JCR - Q2 (*Chemistry, Analytical*) / CiteScore - Q2 (*Mechanical Engineering*)

Contact Us

Micromachines Editorial Office
MDPI, St. Alban-Anlage 66
4052 Basel, Switzerland

Tel: +41 61 683 77 34
www.mdpi.com

mdpi.com/journal/micromachines
micromachines@mdpi.com
[X@micromach_mdpi](https://twitter.com/micromach_mdpi)